

August 5, 2005



## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicants:

KAWAGUCHI et al

Serial No.:

10/083,252

Filed:

February 27, 2002

For:

Plasma Processing Method And Apparatus

Art Unit:

1763

Examiner:

R. Kackar

## <u>AMENDMENT</u>

Mail Stop: Amendment (Fee) Commissioner For Patents P.O. Box 1450

Alexandria, VA 22313-1450

Sir:

The following amendments and remarks are respectfully submitted in connection with the above-identified application, in response to the Office Action dated April 5, 2005. The amendments are listed below and set forth on the following pages.

Amendments to the Claims; and

Remarks are included following the amendments.